

Interoffice
Communication

To: OSHA File

From: Randy Istre
Date: April 12, 1990

Subject: Detected Areas in Blank Wafers

VISTA

In determining the 95% confidence limit for EDC, several added steps were taken because of detected areas appearing in blank Organic Vapor Monitor Wafers which have the same retention time as EDC. Ten blank monitor wafers were tested. An average wafer blank area of 1360 was determined for EDC. This determination was made by measuring peak heights of other peaks (in millimeters) and dividing these lengths into their own areas. The average of these, (82) was multiplied by the peak height for EDC in each monitor blank chromatograph to get ten corrected areas for EDC. The average of these is 1360.

Randy Istre
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Lab Analyst

lk
cc: PLF

Blank Wafer
1360

EDC

VVV 000017857

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*Blank Wafers
95% Confidence Limit*

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